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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/800,421	03/12/2004	Raymond H. Kraft	044182/308725	8419
7590 06/16/2005				
Pillsbury Winthrop LLP Intellectual Property Group Suite 200 11682 El Camino Real San Diego, CA 92130-2092			EXAMINER ROBBINS, JANET L	
			ART UNIT 2857	PAPER NUMBER

DATE MAILED: 06/16/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

AK

<b>Office Action Summary</b>	<b>Application No.</b>	<b>Applicant(s)</b>	
	10/800,421	KRAFT, RAYMOND H.	
	<b>Examiner</b>	<b>Art Unit</b>	
	Janet Robbins	2857	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --  
**Period for Reply**

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

**Status**

- 1) ☒ Responsive to communication(s) filed on 18 October 2004.
- 2a) ☐ This action is **FINAL**.                      2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

**Disposition of Claims**

- 4) ☒ Claim(s) 1-22 is/are pending in the application.
- 4a) Of the above claim(s) \_\_\_\_\_ is/are withdrawn from consideration.
- 5) ☐ Claim(s) \_\_\_\_\_ is/are allowed.
- 6) ☒ Claim(s) 1-6, 11-16 and 18-21 is/are rejected.
- 7) ☒ Claim(s) 7-10, 17 and 22 is/are objected to.
- 8) ☐ Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

**Application Papers**

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 03/12/04 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.  
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).  
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

**Priority under 35 U.S.C. § 119**

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All    b) ☐ Some \*    c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- \* See the attached detailed Office action for a list of the certified copies not received.

**Attachment(s)**

- |  |   |
|--|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892)                        | 4) <input type="checkbox"/> Interview Summary (PTO-413)                     |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948)               | Paper No(s)/Mail Date. _____  |
| 3) <input checked="" type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| Paper No(s)/Mail Date _____  | 6) <input type="checkbox"/> Other: _____                                    |

## DETAILED ACTION

### *Claim Rejections - 35 USC § 103*

1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

2. Claims 1 and 4 are rejected under 35 U.S.C. 103(a) as being unpatentable over Wang et al. ("Physical model-based non-rigid registration incorporating statistical shape information") and further in view of Ishida et al. (US Patent 6,067,373).

With respect to claim 1, Wang et al. teaches a method of point matching measured points to template points (pg 7, col 1, ln 3-7; Fig. 1; pg 8, col 2, ln 4-5; pg 9, col 1, ln 4-7; pg 10, col 1, ln 8-10; pg 12, col 1, ln 40-42); said method comprising:

acquiring measured data representing a set of measured point locations (Fig. 1: a, d [bottom]; pg 7, col 1, ln 3-7; Fig. 2: b, f; Fig. 3: f; Fig. 6; pg 16, col 1, ln 7-10; pg 15, col 1, ln 6-8);

comparing said set of measured point locations to template data (pg 7, col 1, ln 3-7; pg 9, col 2, ln 11-12; Fig. 1-4, 6, 9, 11, 12) representing a set of template point locations (pg 7, col 1, ln 3-7; Fig. 1: a, d [top]; Fig. 2: a, e; pg 12, col 1, ln 23-26);

determining force field vectors (pg 7, abstract, ln 5-7; Fig. 2: d, h; Fig. 3: d, h) operative to perturb said measured point locations into alignment with said template point locations (Fig. 1-4); and

responsive to said defining, matching measured point locations to template point locations (Fig 2: g; Fig. 3: g).

Wang et al. does not perturb the measured points (study image) to match the template points (atlas image), but rather moves the atlas image to align with the study image. Ishida et al. shifts the second image (measured) to align with the first image (template) (Ishida et al.: Fig. 4E-1: 4040; col 2, ln 33-37; col 3, ln 32-35; col 10, ln 50-67) as is described in the immediate application. It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. to alter the measured image as done by Ishida et al. because Ishida et al. discloses methods of altering the first image alone, the second image alone, and both images at the same time. Thus Ishida discloses all combinations including that of altering, or perturbing, the measured data to correspond with the template data.

With respect to claim 11, Wang et al. in view of Ishida et al. discloses a computer readable medium encoded with data and instructions (Ishida et al.: col 19, ln 20-21) for point matching measured points to expected points (Wang et al.: pg 7, col 1, ln 3-7; Fig. 1; pg 8, col 2, ln 4-5; pg 9, col 1, ln 4-7; pg 10, col 1, ln 8-10; pg 12, col 1, ln 40-42); said data and said instructions causing an apparatus executing said instructions to:

acquire measured data representing a set of measured point locations (Wang et al.: Fig. 1: a, d [bottom]; pg 7, col 1, ln 3-7; Fig. 2: b, f; Fig. 3:f; Fig. 6; pg 16, col 1, ln 7-10; pg 15, col 1, ln 6-8);

compare said set of measured point locations (Wang et al.: pg 7, col 1, ln 3-7; pg 9, col 2, ln 11-12; Fig. 1-4, 6, 9, 11, 12) to reference data representing a set of expected

point locations (Wang et al.: pg 7, col 1, ln 3-7; Fig. 1: a, d [top]; Fig. 2: a, e; pg 12, col 1, ln 23-26);

define force field vectors and moment arms (Wang et al.: pg 7, abstract, ln 5-7; Fig. 2: d, h; Fig. 3: d, h) operative to perturb said measured point locations into alignment with said expected point locations (Fig. 1-4); and  
selectively repeat (Wang et al. (convergence): pg 14, section 5, paragraph 1):

comparing, to said reference data, said measured point locations perturbed by said force field vectors and said moment arms (Ishida et al.: Fig. 4A,B, Fig. 4E-1,2) and  
redefining said force field vectors and said moment arms responsive to said comparing (Ishida et al.: Fig. 4B,D);

until predetermined convergence criteria have been satisfied (Ishida et al.: col 10, ln 11-14).

Wang et al. does not perturb the measured points (study image) to match the template points (atlas image), but rather moves the atlas image to align with the study image. Ishida et al. shifts the second image (measured) to align with the first image (template) (Ishida et al.: Fig. 4E-1: 4040; col 2, ln 33-37; col 3, ln 32-35; col 10, ln 50-67) as is described in the immediate application. It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. to alter the measured image as done by Ishida et al. because Ishida et al. discloses methods of altering the first image alone, the second image alone, and both images at the same time. Thus Ishida discloses all combinations including that of altering, or perturbing, the measured data to correspond with the template data.

With respect to claims 4 and 14, Wang et al. teaches utilizing a one-to-one point matching algorithm (pg 8, col 2, ln 4-5; pg 9, col 1, ln 20-21).

With respect to claims 6 and 16, as noted above Wang et al. and Ishida et al. teach parent claims 1 and 11. Ishida et al. further teaches creating said force field vectors to act over a prescribed range (col 10, ln 56-64). It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. to include the range of Ishida et al. because each range denotes a search area where the image is to be analyzed.

3. Claims 2 and 12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Wang et al. ("Physical model-based non-rigid registration incorporating statistical shape information"), in view of Ishida et al. (US Patent 6,067,373), and further in view of Bove Jr. et al. (US Patent 5,946,425). As noted above Wang et al. and Ishida et al. disclose all the conditions of parent claims 1 and 11. They do not teach matching comprising utilizing a many-on-many point matching algorithm. Bove Jr. et al. teaches a method of comparing images based on vector mapping small regions of pixels, or blocks of pixels (col 5, ln 18,33-36,43-57). It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. and Ishida et al. to include the many-on-many point matching algorithm of Bove Jr. et al. because by not operating at a pixel-to-pixel level the overall image is not compromised by spurious missing data (Bove Jr. et al.; col 2, ln 24-27)

4. Claims 3 and 13 are rejected under 35 U.S.C. 103(a) as being unpatentable over Wang et al. ("Physical model-based non-rigid registration incorporating statistical shape

information"), in view of Ishida et al. (US Patent 6,067,373), in view of Bove Jr. et al. (US Patent 5,946,425), and further in view of Strom (US Patent 6,414,477). As noted above Wang et al., Ishida et al., and Bove Jr. et al. teach parent claims 2 and 12. Wang et al. also teaches determining the rotation between said measured point locations and template point locations (Wang et al.: pg 11, col 1, ln 2). These references do not explicitly teach determining offsets and position errors between said measured point locations and said template point locations. Strom teaches finding offset values and error values between the probe card (template) and scrub marks (measured) (col 6, ln 47-52). It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al., Ishida et al., and Bove Jr. et al. to include the offsets and position errors of Strom because the offsets and position errors determine the force field vectors involved in the primary reference.

5. Claims 5, 15, 18, 19, 20, and 21 are rejected under 35 U.S.C. 103(a) as being unpatentable over Wang et al. ("Physical model-based non-rigid registration incorporating statistical shape information"), in view of Ishida et al. (US Patent 6,067,373), and further in view of Strom (US Patent 6,414,477).

With respect to claim 18, Wang et al. and Ishida et al. teach all the elements that claim 11 and claim 18 have in common. They do not teach the invention in the realm of a probe card analyzer system. Strom teaches a method of measuring probe locations in a probe card analyzer system (col 1, ln 6-9). It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. and Ishida et al. to bring the invention into the realm of probe card analyzers because it

is necessary to minimize error values related to the data sets provided by probe machine combination tolerances in the same manner as described by Wang et al. for medical data.

With respect to claim 19, Wang et al., Ishida et al. and Strom teach all the elements of parent claim 18. Strom further teaches utilizing an imaging apparatus (col 5, ln 20-21). It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. and Ishida et al. to bring the invention into the realm of probe card analyzers because it is necessary to minimize error values related to the data sets provided by probe machine combination tolerances and the imaging apparatus is vital to gaining the original image for evaluation.

With respect to claims 5, 15, and 20, as noted above Wang et al. and Ishida et al. teach parent claims 4, 14 and 18. Wang et al. also teaches determining the rotation between said measured point locations and template point locations (Wang et al.: pg 11, col 1, ln 2). These references do not explicitly teach determining offsets and position errors between said measured point locations and said template point locations. Strom teaches finding offset values and error values between the probe card (template) and scrub marks (measured) (col 6, ln 47-52). It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. and Ishida et al. to include the offsets and position errors of Strom because the offsets and position errors determine the force field vectors involved in the primary reference.



With respect to claim 21, as noted above Wang et al., Ishida et al., and Strom teach parent claim 18. Ishida et al. further teaches creating said force field vectors to act over a prescribed range (col 10, ln 56-64). It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the teachings of Wang et al. and Ishida et al. to bring the invention into the realm of probe card analyzers because it is necessary to minimize error values related to the data sets provided by probe machine combination tolerances.

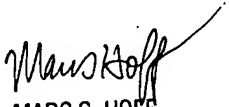
***Allowable Subject Matter***

6. Claims 7, 8, 9, 10, 17, and 22 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Janet Robbins whose telephone number is 571-272-8584. The examiner can normally be reached on weekdays from 8:00am - 4:30pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Marc Hoff can be reached on 571-272-2216. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

JLR  
June 10, 2005

  
MARC S. HOFF  
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